

# Microstructure and Environmental Stability of Plasma-Enhanced ALD TiO<sub>2</sub>/SiO<sub>2</sub> Multilayer Anti-Reflective Films on PMMA Substrates

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## Results and Discussion

Plasma-enhanced atomic layer deposition (PEALD) has been utilized to deposit anti-reflective (AR) coatings on plastic substrates. At a deposition temperature of 70°C, it was found that the refractive index of TiO<sub>2</sub> and SiO<sub>2</sub> increased with higher plasma power due to enhanced precursor reactivity and film density, as shown in Figure 1,2. However, high-energy ion bombardment during multi-layer deposition caused cracks on the plastic surface, making 50W the optimal plasma power.

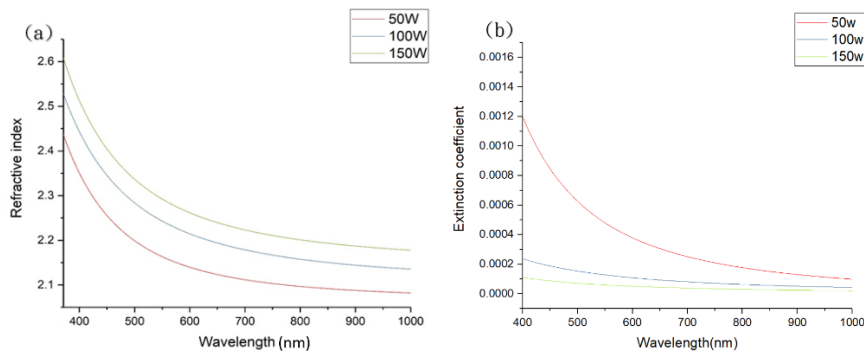


Figure 1. (a) refractive index (n) and (b) extinction coefficient (k) of TiO<sub>2</sub> under varying laser powers.

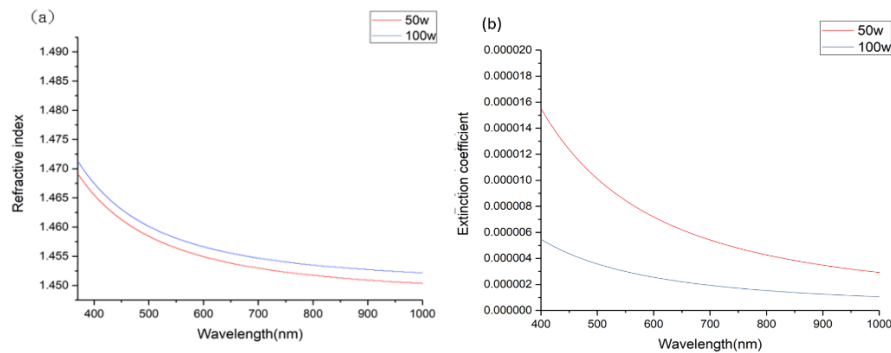


Figure 2. (a) refractive index (n) and (b) extinction coefficient (k) of SiO<sub>2</sub> under varying laser powers.

At low temperature (70°C) and low plasma power (50W), TiO<sub>2</sub> films showed no significant crystallization. Crystallinity strength increased slightly from 82 to 117 as film thickness increased, indicating a microcrystalline state, as shown in Figure 2(a). In figure 2(b), surface roughness remained low, around 0.28 nm, demonstrating very flat TiO<sub>2</sub> films suitable for AR coatings.

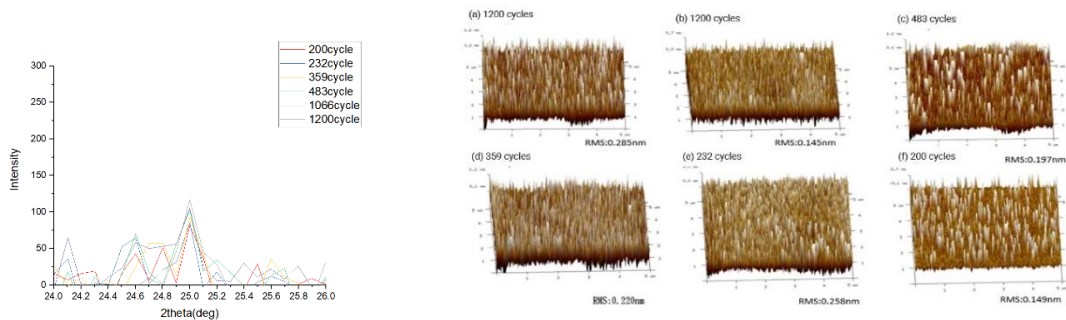


Figure 2. (a) Crystallization strength (b) Roughness of TiO<sub>2</sub> at different cycle times (film thickness).

Under harsh conditions (85°C, 85% RH), AR coatings without inhibition layers lasted up to 998 hours before cracking. Inserting 2 to 4 layers of 1.5 nm SiO<sub>2</sub> into TiO<sub>2</sub> reduced durability from 506 to 209 hours, indicating that more insertion layers weakened the film structure, as shown in Figure 3. Figure 4 depicts the TEM results of AR coatings with varying structural layers, incorporating 2 to 4 layers of 1.5 nm SiO<sub>2</sub> inserted into TiO<sub>2</sub>. The decreased durability with SiO<sub>2</sub> insertion was attributed to lower TiO<sub>2</sub> thickness and density, making the films more susceptible to moisture penetration and erosion in high humidity.

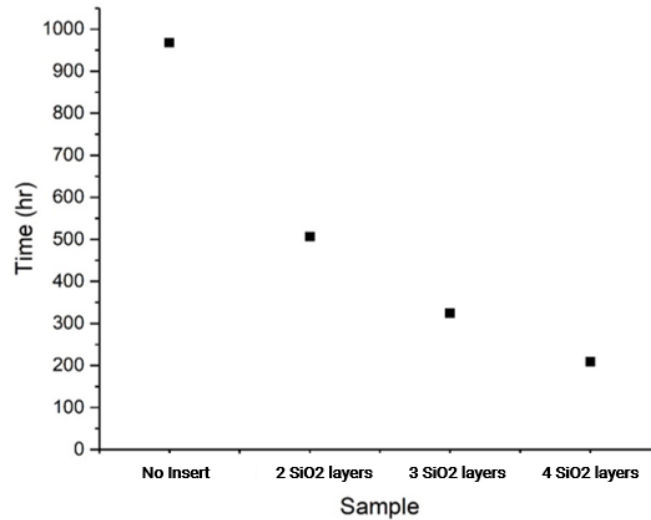


Figure 3. Impact of the numbers of SiO<sub>2</sub> Interlayer on AR Coating Durability (85°C, 85% RH).

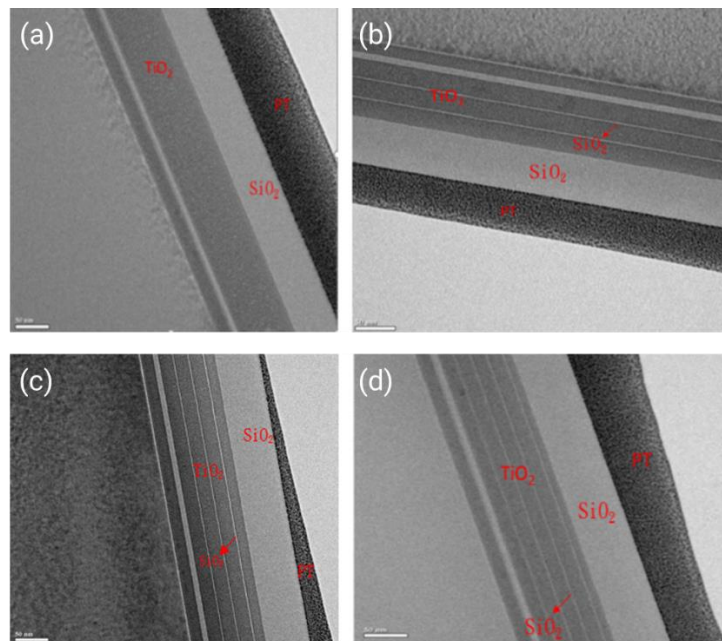


Figure 4. TEM results of different layer structures of AR films (a) Not intercalated (b) Inserted with 2 layers of SiO<sub>2</sub> (c) Inserted with 3 layers of SiO<sub>2</sub> (d) Inserted with 4 layers of SiO<sub>2</sub>.

Thicker, denser TiO<sub>2</sub> films in non-inserted layers resulted in lower water vapor transmission rates (WVTR) and better durability under constant temperature and humidity testing.